

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10689617			
<b>Filing Date:</b>	22-Oct-2003			
<b>Title of Invention:</b>	Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device			
<b>First Named Inventor:</b>	Satoru Okamoto			
<b>Filer:</b>	John F. Hayden/Christine Tomlinson			
<b>Attorney Docket Number:</b>	12732-170001			
Filed as Large Entity				
<b>Utility Filing Fees</b>				
<b>Description</b>	<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Post-Allowance-and-Post-Issuance:				
<b>Extension-of-Time:</b>				
Extension - 2 months with \$0 paid	1252	1	450	450

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				450